

# UNITED STATES PATENT AND TRADEMARK OFFICE

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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/819,688	03/29/2001	Eiji Natori	109120	3149	
25944	7590 12/30/2002				
OLIFF & BERRIDGE, PLC			EXAMINER		
P.O. BOX 199		HOGANS, DAVID L			
ALEXANDRI	A, VA 22320				
			ART UNIT	PAPER NUMBER	
			2813		
			DATE MAILED: 12/30/2002	15	

Please find below and/or attached an Office communication concerning this application or proceeding.

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		Application	No.	Applicant(s)				
Office Action Summary		09/819,688		NATORI, EIJI				
		Examiner		Art Unit				
<b>4</b>		David L. Hog	ans	2813				
The MAILING DATE of this communication appears on the cover sheet with the correspondence address								
Period for Reply A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM								
THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.  - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.  - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).  - Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).  Status								
1)⊠ 1	Responsive to communication(s) filed on <u>0</u>	9 October 2002	•					
2a) <u></u> □	This action is <b>FINAL</b> . 2b)⊠	This action is no	n-final.					
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.  Disposition of Claims								
• 4)⊠ Claim(s) <u>1-13 and 15-17</u> is/are pending in the application.								
4a) Of the above claim(s) is/are withdrawn from consideration.								
5) Claim(s) is/are allowed.								
6)⊠ Claim(s) <u>1-13 and 15-17</u> is/are rejected.								
7) 🗌 C	claim(s) is/are objected to.							
8) 🗌 C	claim(s) are subject to restriction and	d/or election requ	uirement.					
Application	n Papers							
9) The specification is objected to by the Examiner.								
10)⊠ The drawing(s) filed on <u>29 March 2001</u> is/are: a)⊠ accepted or b)⊡ objected to by the Examiner.								
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).								
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.								
If approved, corrected drawings are required in reply to this Office action.								
12) The oath or declaration is objected to by the Examiner.								
Priority under 35 U.S.C. §§ 119 and 120								
13) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).								
a) ☐ All b) ☐ Some * c) ☑ None of:								
	<ul><li>1. Certified copies of the priority documents have been received.</li><li>2. Certified copies of the priority documents have been received in Application No</li></ul>							
3. Copies of the certified copies of the priority documents have been received in this National Stage								
application from the International Bureau (PCT Rule 17.2(a)).  * See the attached detailed Office action for a list of the certified copies not received.								
14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).								
a) ☐ The translation of the foreign language provisional application has been received.  15)☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.								
Attachment(s)								
2) Notice	of References Cited (PTO-892) of Draftsperson's Patent Drawing Review (PTO-948) ation Disclosure Statement(s) (PTO-1449) Paper No(	5	Interview Su Notice of Int Other: See	ımmary (PTO-413) Paper No ormal Patent Application (PT <i>Attaches</i> .	o(s) -ro-152)			

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#### **DETAILED ACTION**

This Office Action is in response to Amendment A filed on October 9, 2002.

#### Status of Claims

Claims 1-13 and 15-17 are pending. Claim 14 has been cancelled.

### Election/Restrictions

1. Applicant's election with traverse of Group I/Claims 1-17 in Paper No. 14 is acknowledged. The traversal is on the ground(s) that Group I and Group II are drawn to sufficiently inter-related subject matter and thus does not create a serious examination burden. This is not found persuasive because the inventions of Group I and II have acquired a separate status within the art. As proof of this, the April 10, 2002, Election/Restriction Detailed Action cited different classifications for the claimed inventions.

Therefore, since the different classifications provides an undue examining burden upon the Examiner, the Restriction Requirement is still deemed proper and is therefore made FINAL.

## Claim Rejections - 35 USC § 102

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

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3. Claims 1, 4 and 6-11 are rejected under 35 U.S.C. 102(e) as being anticipated by

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6,110,531 to Paz de Araujo et al. (hereinafter Paz).

Claim 1

In reference to Claim 1, Paz et al. teaches:

a method of mixing a ferroelectric precursor with an active species and applying

the film by a misted CVD process (See column 5 lines 21-30 and lines 45-56,

columns 13-14 lines 50-10 and Figure 3)

Claim 4

In reference to Claim 4, Paz et al. teaches:

electrically charging the fine particles (136 and 137) (See Figure 3 and column 8

lines 8-30)

Claim 6

In reference to Claim 6, Paz et al. teaches:

the active species is a radical or ion (136 and 137) (See Figure 3 and column 5

lines 21-30 and column 8 lines 8-30)

Claim 7

In reference to Claim 7, Paz et al. teaches:

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the active species is radical or ion (136 and 137) of the raw material species
 (113A, B or C) (See Figure 3 and column 5 lines 21-30 and column 8 lines 8-30)

#### Claim 8

In reference to Claim 8, Paz et al. teaches:

• the active species is an ion of oxygen (112C) or nitrogen (112B) (See Figure 3)

#### Claims 9 and 10

In reference to Claims 9 and 10, Paz et al. teaches:

• the active species is an ion or radical of inert argon gas (112A) (See Figure 3)

#### Claim 11

In reference to Claim 11, Paz et al. teaches:

the active species is fed to the substrate in an accelerated state (136 and 137)
 (See Figure 3)

# Claim Rejections - 35 USC § 103

- 4. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

5. Claims 1, 2, 5 and 15-17 are rejected under 35 U.S.C. 103(a) as being unpatentable over 6,232,167 to Satoh et al. in view of 5,456,945 to McMillan et al. Claim 1

Satoh et al. teaches a ceramic material formed on a substrate by heating and vaporizing Bismuth raw material and mixing it with Argon and Oxygen gas for deposition on a substrate. (See column 7 lines 14-26 and column 8 lines 35-60)

Satoh et al. fails to explicitly teach forming the ceramic film by LSMCD or a misted CVD process.

However, McMillan et al, in column 4 lines 55-60 and column 8 lines 10-25, teaches a ferroelectric layer that is deposited by a misted CVD process. Further, McMillan teaches that high quality complex thin films (@ 200 A°), such as ferroelectric films, can be readily achieved by the misted CVD process. (See column 6 lines 35-45 and column 7 lines 50-55)

It would have been obvious to one of ordinary skill in the art to modify Satoh et al. by incorporating deposition of a ferroelectric film by misted CVD, as taught by McMillan et al., to produce high quality thin ferroelectric films (@ 200 A°).

Claim 2

Incorporating all arguments of Claim 1 and noting that Satoh et al. teaches a diameter of fine raw material that is 50 nm (See column 9 lines 1-5)

Claim 5

Incorporating all arguments of Claim 1 and noting that Satoh et al. teaches a fine particle raw material that is gasified before mixing with the reaction gas (See column 7 lines 16-20 and column 8 lines 35-60)

Claim 15

Incorporating all arguments of Claim 1 and noting that Satoh et al. teaches the ceramic film is a dielectric (See Figure 1 and column 11 lines 35-47)

Claims 16 and 17

Incorporating all arguments of Claim 1 and noting that Satoh et al. teaches a dielectric formed at 400 °C (See column 8 lines 57-59 and column 9 lines 53-61)

6. Claim 3 is rejected under 35 U.S.C. 103(a) as being unpatentable over 6,232,167 to Satoh et al. in view of 5,456,945 to McMillan et al. further in view of 6,146,905 to Chivukula et al.

Claim 3

Incorporating all arguments of Claim 1 above and noting that Satoh et al. and McMillan et al. fail to explicitly teach a diameter of fine particle that is 0.01 micrometer of less.

However, Chivukula et al., in column 6 lines 37-40, teaches a particle diameter of 10 nm. Further, Chivukula et al. discloses that a superior high frequency response is noted in integrated circuits that are formed form reproducible small grain size ferroelectric layers.

It would have been obvious to one of ordinary skill in the art to modify Satoh et al. and McMillan et al. by incorporating a ferroelectric particle diameter of 10 nm, as taught by Chivukula et al., to produce a superior high frequency response in ferroelectric films.

7. Claim 12 is rejected under 35 U.S.C. 103(a) as being unpatentable over 6,232,167 to Satoh et al. in view of 5,456,945 to McMillan et al. further in view of 5,563,762 to Leung et al.

Incorporating all arguments of Claim 1 and noting that Satoh et al. and McMillan et al. fail to explicitly teach a ceramic film formed on part of a substrate.

However, Leung et al., in Figure 3 and column 8 lines 25-30, teaches a ferroelectric dielectric material that is selectively deposited on a bottom electrode. Further, Leung et al. teaches the selective deposition so that an isolated capacitor structure may be made.

It would have been obvious to one of ordinary skill in the art to modify Satoh et al. and Mcmillan et al. by incorporating selective deposition of a ferroelectric film, as taught by Leung et al., to create an isolated capacitor structure.

8. Claim 13 is rejected under 35 U.S.C. 103(a) as being unpatentable over 6,232,167 to Satoh et al. in view of 5,456,945 to McMillan et al. in view of 5,563,762 to Leung et al. further in view of 5,932,904 to Hsu et al and further in view of 6,207,236 to Araki et al.

Incorporating all arguments of Claim 1 and noting that Satoh et al., McMillan et al. and Leung et al. fail to explicitly teach a film-forming region on a substrate having an affinity for ceramics with a non-film-forming region having no affinity for ceramics.

However, Leung et al., in Figure 3 and column 8 lines 25-30, teaches a ferroelectric dielectric material that is selectively deposited on a bottom electrode. Further, Hsu et al., in column 4 lines 20-25, teaches that Iridium or Iridium Oxide is a suitable conductive material to deposit a ferroelectric layer upon. Furthermore, Araki et al., in column 4 lines 11-33, teaches that fluorine containing compounds have excellent non-sticking property when used as a coating compound. Such functional use of Iridium or Iridium Oxide as a suitable conductive material, such selective deposition as taught by Leung et al., and such non-sticking properties of Fluorine containing material as

taught by Araki et al., renders these applications obvious to Satoh et al. and McMillan et al.

It would have been obvious to one of ordinary skill in the art to modify Satoh et al., McMillan et al. and Leung et al. by incorporating the selective deposition of a ferroelectric material upon Iridium or Iridium Oxide and not upon a Fluorine containing compound, as taught by Hsu et al. and Araki et al., to selectively deposit a ferroelectric film on a microelectronic structure.

### Response to Arguments

6. Applicant's arguments with respect to claims 1-13 and 15-17 have been considered but are moot in view of the new ground(s) of rejection.

#### Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to David L. Hogans whose telephone number is (703) 305-3361. The examiner can normally be reached on M-F (7:30-4:30).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead Jr. can be reached on (703) 308-4940. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 308-7722 for regular communications and (703) 308-7724 for After Final communications.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-1782.

dh DA

December 24, 2002

CARL WHOTEHEAD, JR.

SUPERVISORY PATENT EXAMINEF
TECHNOLOGY CENTER 2800

## Continuation Sheet (PTO-326)

Application No.

The Office has not received a certified copy of Japan 2000-91604.